

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
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Examiner		Art Unit		Page 1 of 1
Binh X. Tran		1713		

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*	B	US-2002/0102490	08-2002	Ito et al.	430/270.1
*	C	US-5,981,616	11-1999	Yamamura et al.	522/168
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	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Chou, Krauss and Renstrom, "Nanolithography", Journal Vacuum Science Technology B 14 (6); pages 4129-4133; 1996
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.